

Serial No. 10/790,412
Attorney Docket No. H1648
Firm Reference No. AMDSPH1648US

Reply to Office Action Dated August 5, 2004
Reply Dated October 28, 2004

REMARKS

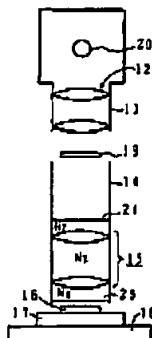
Following entry of the above amendment, claims 1-21 will be pending. Claims 2 and 12 have been amended without change in scope to correct an obvious typographical error. Specifically, the term "flourine" has been replaced with the term "fluorine" in each claim. Withdrawal of the objection is respectfully requested. Additionally, claims 1, 11 and 21 have been amended to clarify the features of the invention. Specifically, the phrase "the placing of the pellicle is accomplished by a moveable mounting means that translates into the lithographic apparatus in order to position the pellicle in close proximity to the surface of the projection system" has been inserted in claim 1. With regard to claims 11 and 21, the phrase "a moveable mounting means that translates into the lithographic apparatus in order to position the pellicle in close proximity to the surface of the projection system" has been inserted.

I. REJECTION OF CLAIMS UNDER 35 U.S.C. § 102

Claims 1, 4-7, 9, 11 and 14-21 stand rejected under 35 U.S.C. § 102(b) as being anticipated by Fujie et al., U.S. Patent No. 5,696,623 ("Fujie"). Withdrawal of the rejection is respectfully requested for at least the following reasons.

In FIG. 5B reproduced below for the Examiner's convenience, Fujie discloses an optical projection system. Further, Fujie discloses light emitted from a lamp 20 passes through a condenser lens group 12 supported by a lens barrel 11 and illuminates a reticle 13. Additionally, light passed through the reticle 13 passes through a reduction lens system 15 supported by a lens barrel 14, and is focused onto a photoresist film on a semiconductor wafer 16. Fujie also discloses pellicles 24 and 25 of thin films are disposed upstream and downstream of the reduction lens system 15. See, for example, FIG. 5B, Col., lns. 41-50 and 65-67. However, Fujie does not disclose **placing** of a pellicle accomplished by a **moveable mounting means that translates into** a lithographic apparatus in order to position the pellicle in close proximity to a surface of the projection system.

FIG. 5B



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Claim 1 as amended recites, *inter alia*, "the placing of the pellicle is accomplished by a **moveable mounting means that translates into** the lithographic apparatus in order to position the pellicle in close proximity to the surface of the projection system" has been inserted in claim 1. Claims 11 and 21 as amended recite, *inter alia*, "a **moveable mounting means that translates into** the lithographic apparatus in order to position the pellicle in close proximity to the surface of the projection system." In contrast, Fujie discloses the pellicles 24 and 25 are disposed to seal spaces between surfaces of outermost lenses and the external atmosphere. Additionally, Fujie discloses the spaces between the surfaces of the outermost lenses of the reduction lens system 15 and the pellicles 24 and 25 are also filled in with nitrogen gas. See, for example, Col. 8, lns. 1-9.

Thus, Fujie does not disclose a **moveable mounting means that translates into** the lithographic apparatus as recited in amended claims 1, 11 and 21. The moveable mounting means of the present invention significantly reduces the amount of time spent in removing contamination from surfaces of the lithographic lens. Additionally, moveable mounting means provides a relatively easily replacement of the pellicle for the lithographic lens thereby extending the useful life of the lithographic lens.

Therefore, since Fujie does not teach or suggest one or more of the features as claimed in amended claims 1, 11 and 21, claims 1, 11 and 21 and claims 4-7, 9 and 14-20 that depend therefrom are patentable over Fujie.

II. REJECTION OF CLAIMS UNDER 35 U.S.C. § 103

Claims 2, 8 and 12 stand rejected under 35 U.S.C. § 103(a) as being unpatentable over Fujie in view of Nagata, U.S. Patent Application Publication No. 2004/0091796 ("Nagata"). Claims 3, 10 and 13 stand rejected under 35 U.S.C. § 103(a) as being unpatentable over Fujie in view of Hibbs, U.S. Patent No. 6,731,378 ("Hibbs"). Withdrawal of the rejections is respectfully requested for at least the following reasons.

With regard to claims 2, 8 and 12, claims 2 and 8 depend from claim 1 either directly or indirectly. Claim 12 depends from claim 11. Nagata does not make up for the deficiencies of Fujie. That is, Nagata does not disclose placing of a pellicle accomplished by a moveable mounting means that translates into a lithographic apparatus in order to position the pellicle in close proximity to a surface of the projection system as recited in amended claim 1 (see above). Further, Nagata does not disclose a moveable mounting means that translates into a lithographic apparatus in order to position a pellicle in close proximity to a surface of the projection system as recited in amended claim 11 (see above).

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Therefore, since Fujie alone or in combination with Nagata does not teach or suggest one or more of the features of as claimed in amended claims 1 and 11, claims 2, 8 and 11 that depend therefrom are patentable over Fujie and Nagata, alone or in combination.

Regarding claims 3, 10 and 13, claims 3 and 10 depend from claim 1 either directly or indirectly. Claim 13 depends from claim 11. Hibbs does not make up for the deficiencies of Fujie. That is, Hibbs does not disclose placing of a pellicle accomplished by a moveable mounting means that translates into a lithographic apparatus in order to position the pellicle in close proximity to a surface of the projection system as recited in amended claim 1 (see above). Further, Hibbs does not disclose a moveable mounting means that translates into a lithographic apparatus in order to position a pellicle in close proximity to a surface of the projection system as recited in amended claim 11 (see above).

Therefore, since Fujie alone or in combination with Hibbs does not teach or suggest one or more of the features of as claimed in amended claims 1 and 11, claims 3, 10 and 13 that depend therefrom are patentable over Fujie and Hibbs, alone or in combination.

III. CONCLUSION

In light of the foregoing, it is respectfully submitted that the present application is in condition for allowance and notice to that effect is hereby requested. If it is determined that the application is not in condition for allowance, the Examiner is invited to initiate a telephone interview with the undersigned attorney to expedite prosecution of the present invention.

Any additional fee(s) resulting from this communication is hereby authorized to be charged to our Deposit Account No. 18-0988; Our Order No. H1648 (AMDSPH1648US).

Respectfully submitted,
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